



AF 11746

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Yuji ONO et al.

Serial No.: 09/940,788

Corres. and Mail

Group Art Unit: 1746

Filed: August 29, 2001

**BOX AF**

Examiner: Joseph L. Perrin

P.T.O. Confirmation No.: 4613

For: **SINGLE WAFER TYPE SUBSTRATE CLEANING METHOD AND APPARATUS**

**RESPONSE UNDER 37 CFR §1.116**  
**- EXPEDITED RESPONSE -**  
**GROUP ART UNIT 1746**

**MAILSTOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA, 22313-1450

**RECEIVED**  
**JUN 06 2003**  
**TC 1700**

June 4, 2003

Sir:

In response to the Office Action dated **March 11, 2003**, please amend the above-identified application as follows: